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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Toshihito Tsuga, et al.

Docket No: TI-31620

Serial No: 10/085,753

Conf. No: 8409

Examiner: Michail Kornakov

Art Unit: 1746

Filed: 02/28/2002


For: METHOD AND DEVICE FOR REMOVING PARTICLES ON SEMICONDUCTOR WAFERS

AMENDMENT AFTER ALLOWANCE

Mail Stop Issue Fee
Commissioner For Patents
P.O. Box 1450
Alexandria, VA 22313-1450

MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 4-4-05.


Ann Trent

Dear Sir:

Pursuant to 37 C.F.R. 1.312 and subject to the recommendation of the Examiner and the approval of the Commissioner, and without withdrawing the case from issue, kindly amend the subject application as follows: